PATENT =// 29936/37431



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Sung Gyu Pyo

Serial No.: 09/875,698

Filed: June 6, 2001

For: Method of Forming a Metal Wiring in a Semiconductor Device

Group Art Unit: 1765

Examiner: Lynettte T. Umez

Eronini

I hereby certify that this paper is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Commissioner for Patents Washington, DC 20231 on February 4, 2003

Michael R Hull Reg. No. 35,902

Attorney for Applicant

AMENDMENT

Commissioner for Patents Washington, DC 20231

Dear Sir:

In response to the office action mailed on November 4, 2002, please enter the following amendments and remarks.

In the Specification:

Please replace the paragraph beginning on page 4, line 17, with the following rewritten paragraph:

--The chemical enhancer layer 60 is formed in thickness ranging from about 50 to about 500 Å. Materials for forming the chemical enhancer layer 60 may include one of I (iodine)-containing liquid compounds such as CH₃I, C₂H₅I, CD₃I, CH₂I₂ etc., Hhfac1/2H₂O, Hhfac, TMVS, pure I₂, I (iodine)-containing gas and water vapor, and is performed at the temperature ranging from about -20 to about 300°C for a time period ranging from about 1 to about 600 seconds. Also, the materials may include F, CI, Br, I, At of a liquid state and F, CI, Br, I, At of a gas state, which are Group VII elements in the Periodic Table.--

Ai.